JEOL 7000F scanning electron microscope

This Schottky emission gun SEM (1.2 nm resolution at 30kV) is equipped with a conventional Everhart-Thornley secondary detector, a retractable DEBEN-BSED-GEN5 backscatter detector, an Oxford Aztec EDS (energy-dispersive spectrometer) and EBSD (electron backscatter diffraction) system.

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Location: Higgins Lab 047
JEOL 100 CXII transmission electron microscope

This conventional TEM is equipped with a Gatan Orius 830 CCD camera, capable of electron diffraction and diffraction contrast imaging.

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Location: Olin Hall 028
PANalytical Empyrean x-ray diffractometer

This is a multi-function x-ray diffractometer, capable of carrying out powder diffraction, stress analysis, texture analysis, x-ray reflectivity analysis and small-angle x-ray scattering.

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Location: Washburn 231
This spectrometer is used for accurate chemical analysis of metals and alloys.

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Location: Washburn 113
Other equipment

1 Olympus inverted optical microscope (WB336)
1 Clark CM-400AT microhardness tester (WB336)
1 Shimazu HMV-200 microhardness tester (WB336)
3 Rockwell hardness testers (WB336)
1 Buehler microhardness tester (WB336)
3 Buehler vibromet I polishers (WB341)
2 Pace Nano 2000T grinder-polishers (WB341)
3 Century polishers (WB341)
1 EMS sputter coater (HL047)
1 Buehler Electromet 4 electropolisher (WB341)
1 Fischione M110 twin-jet electropolisher (WB113)
1 Mark V 600 cut-off machine (WB341)

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